

SPIS4 Sphere validation

David Rodgers, Simon Clucas,
Alain Hilgers
Jean-Francois Roussel, Jean-Charles
Mateo-Velez, B.Thiebault, J.Forest

SPINE Meeting
28-29 September 2009
ESTEC



Electromagnetics & Space
Environment Division – TEC-EES

Introduction

- New features of SPIS must be shown to be validated
- A simple sphere case was performed before:
 - ‘Modelling of Plasma Probe Interactions With a PIC Code Using an Unstructured Mesh’, A. Hilgers, S. Clucas, B. Thiébault, J.-F. Roussel, J.-C. Matéo-Vélez, J. Forest, and D. Rodgers
- We revisited this case for SPISv4
 - 64-bit java virtual machine
 - BacktrackingPICCompositeVolDistrib

PARAMETERS FOR THE TEST

Quantity	Symbol	Value
Temperature	T	1.0 eV
Electron density	n	10^7 m^{-3}
Debye length	λ	2.35 m
Potential	ϕ	[0,12]V
Sphere radius	r	0.25 m
Number of tetrahedrons		24000
Simulation box diameter		20 m
Number of macro-particles		~100,000

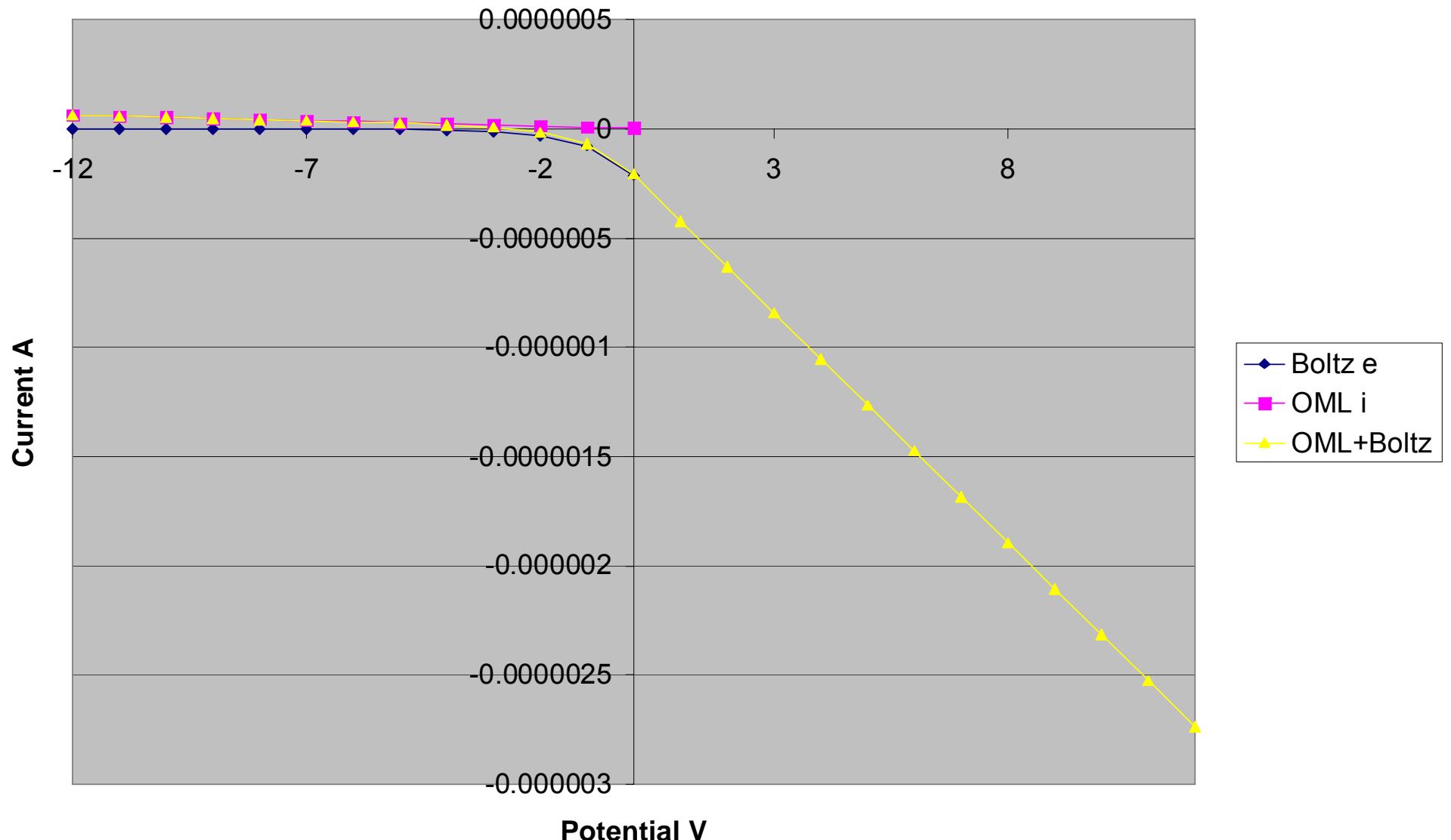
Langmuir probe equations

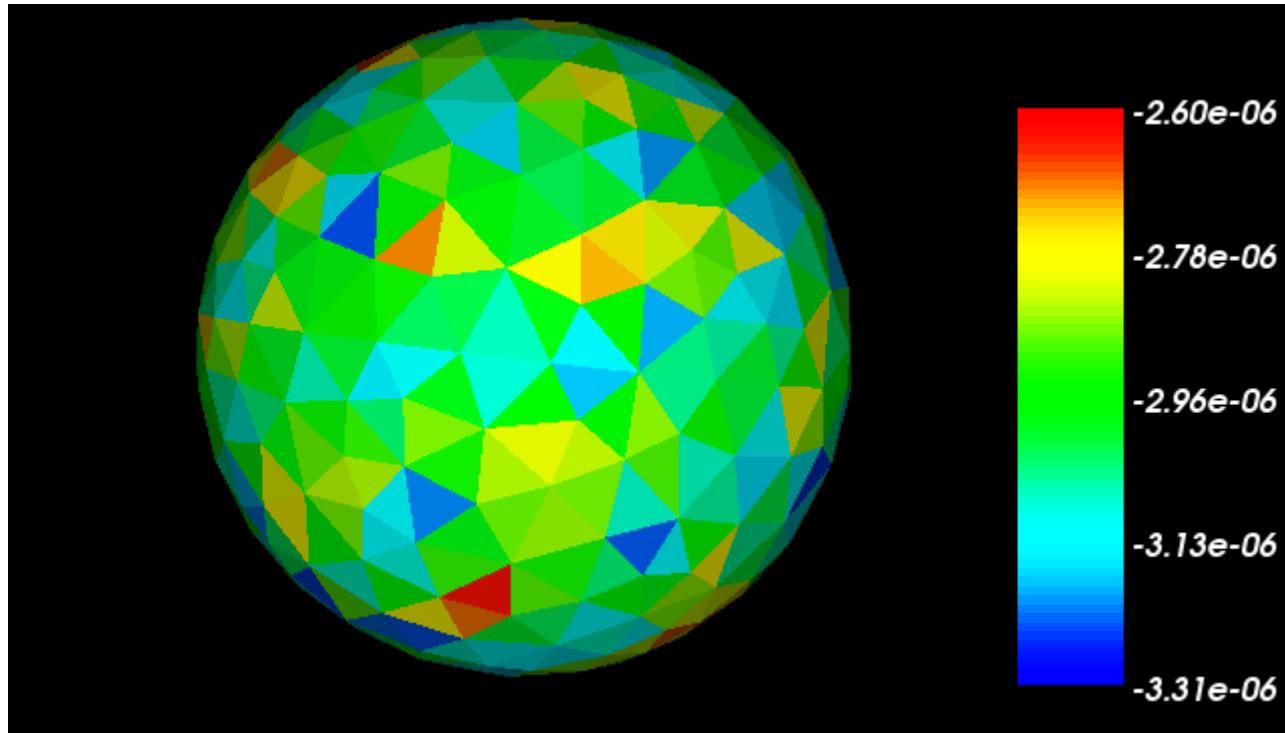
OML – current of attracted species
(valid for thick sheaths)

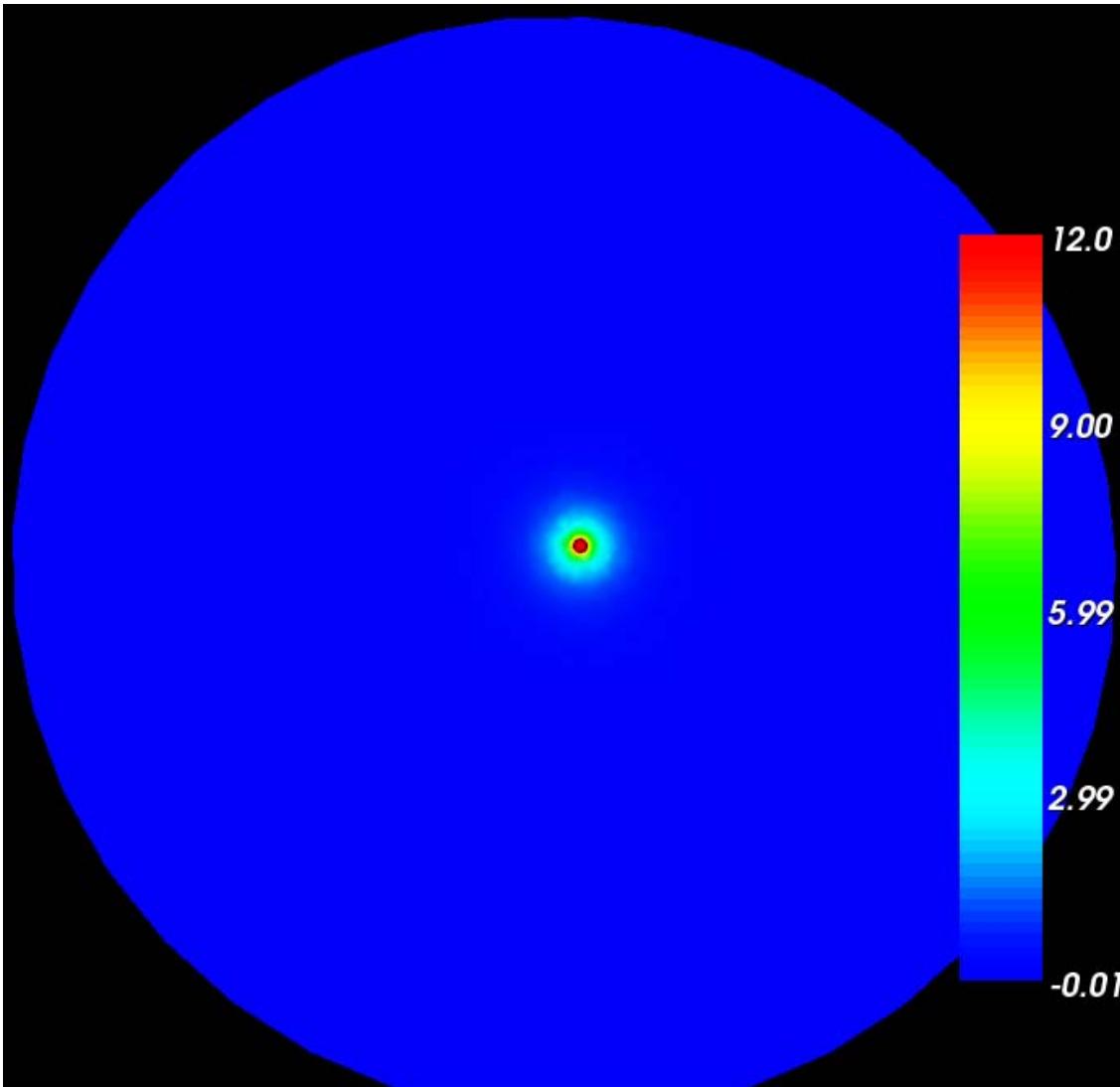
$$I = 4\pi qn \sqrt{\frac{kT}{2\pi m}} \left(1 + \frac{q\phi}{kT}\right) r^2$$

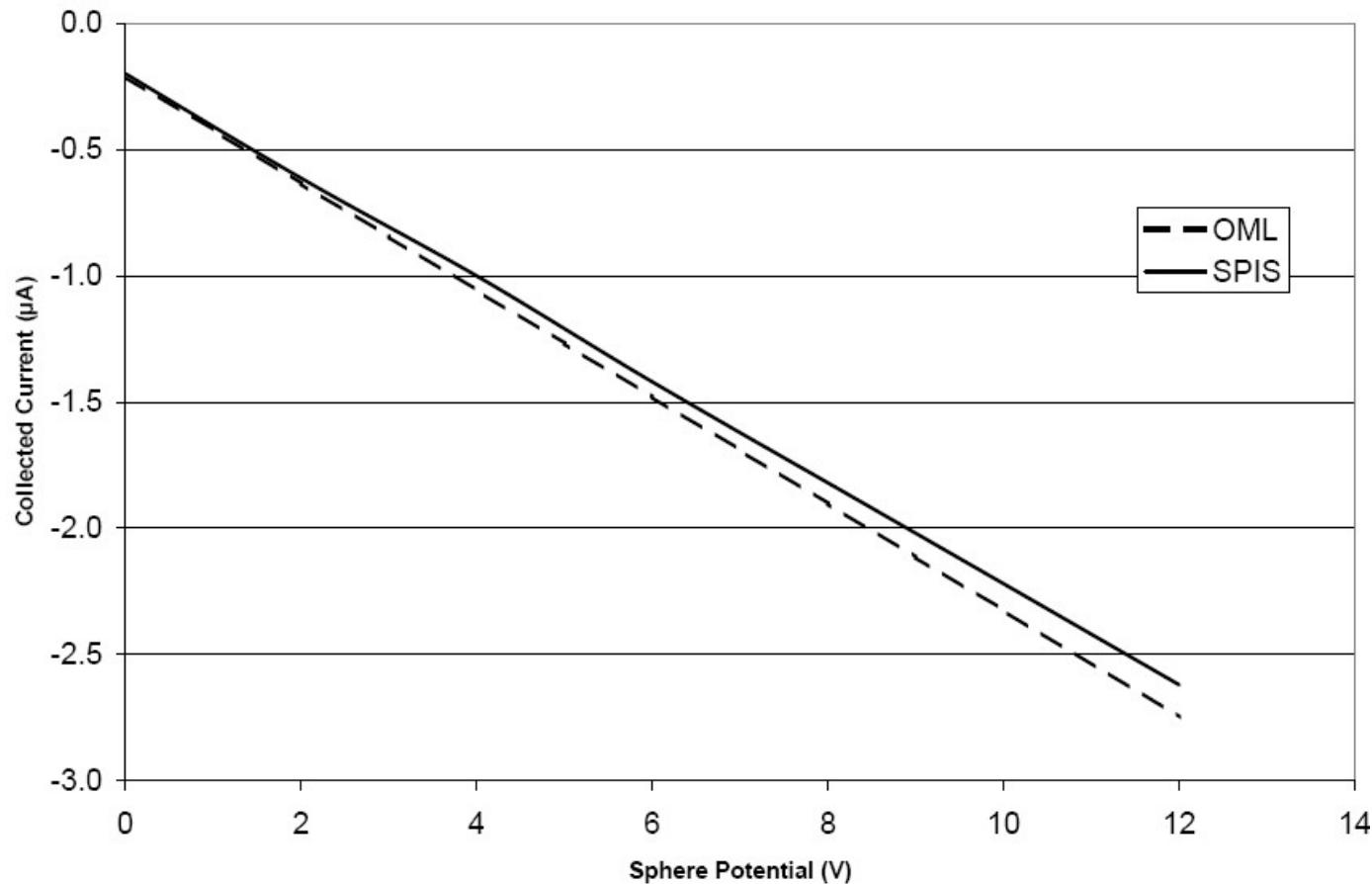
Boltzmann – current of repelled species

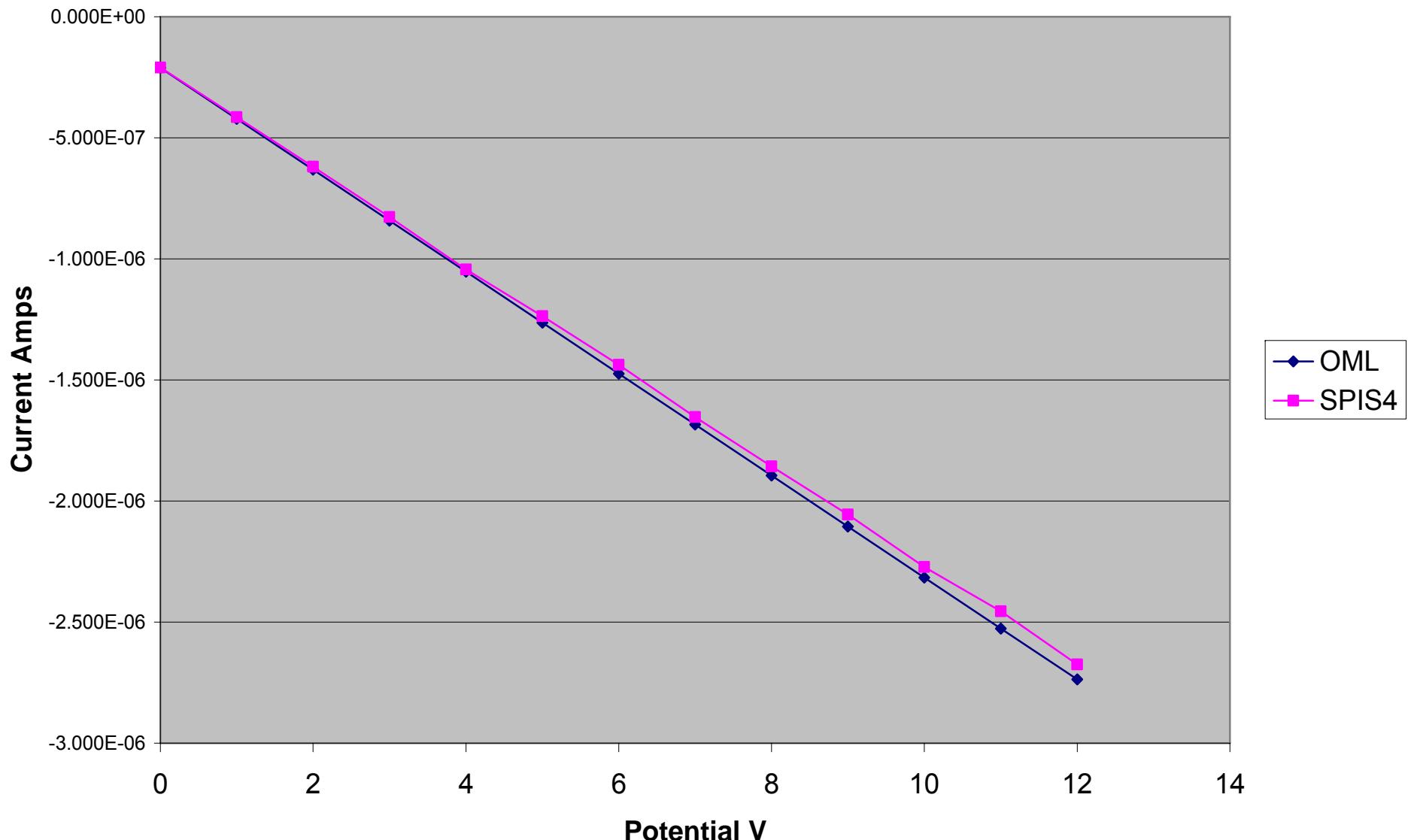
$$I = 4\pi qn \sqrt{\frac{kT}{2\pi m}} \exp\left(\frac{-q\phi}{kT}\right) r^2$$





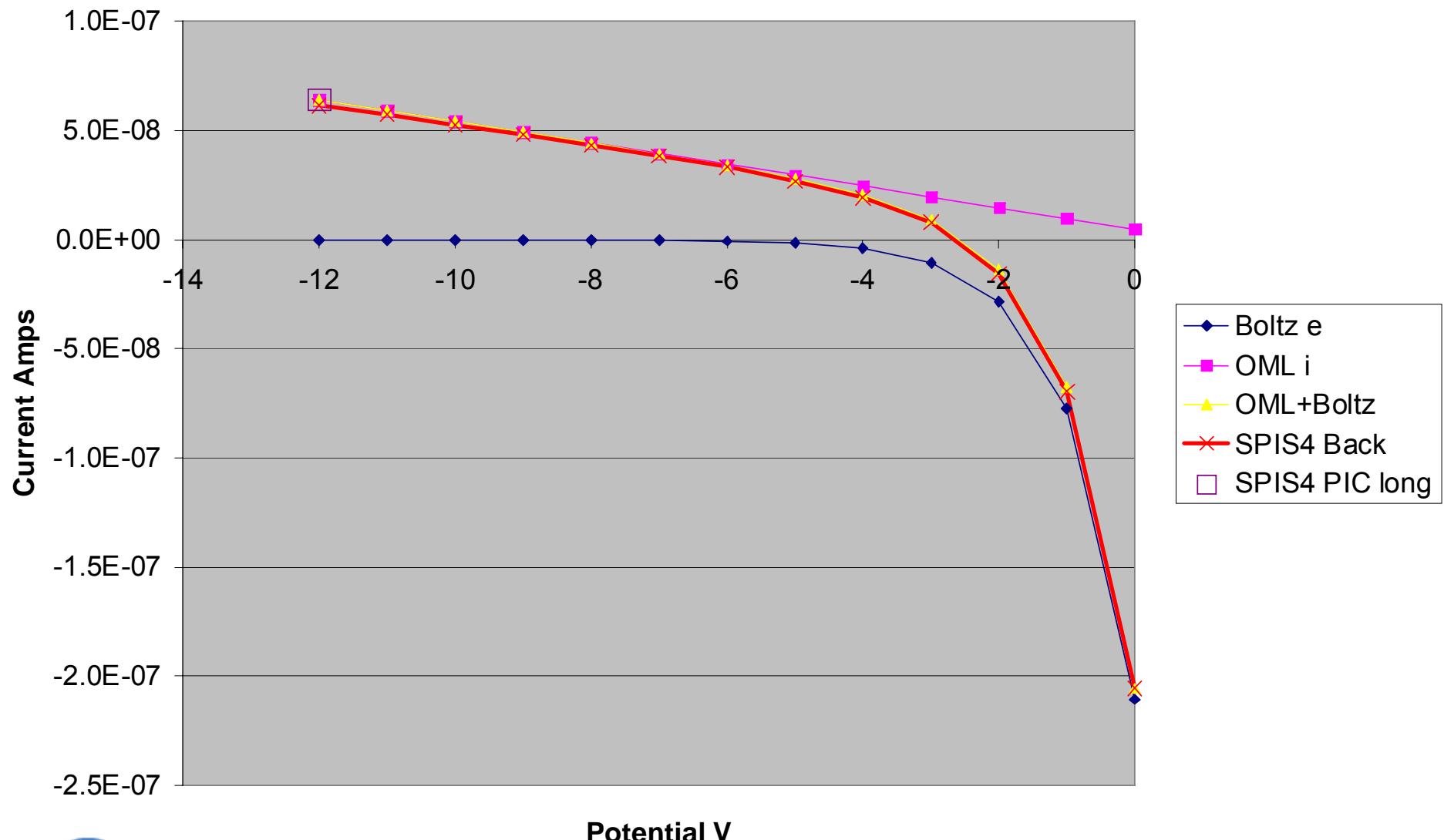






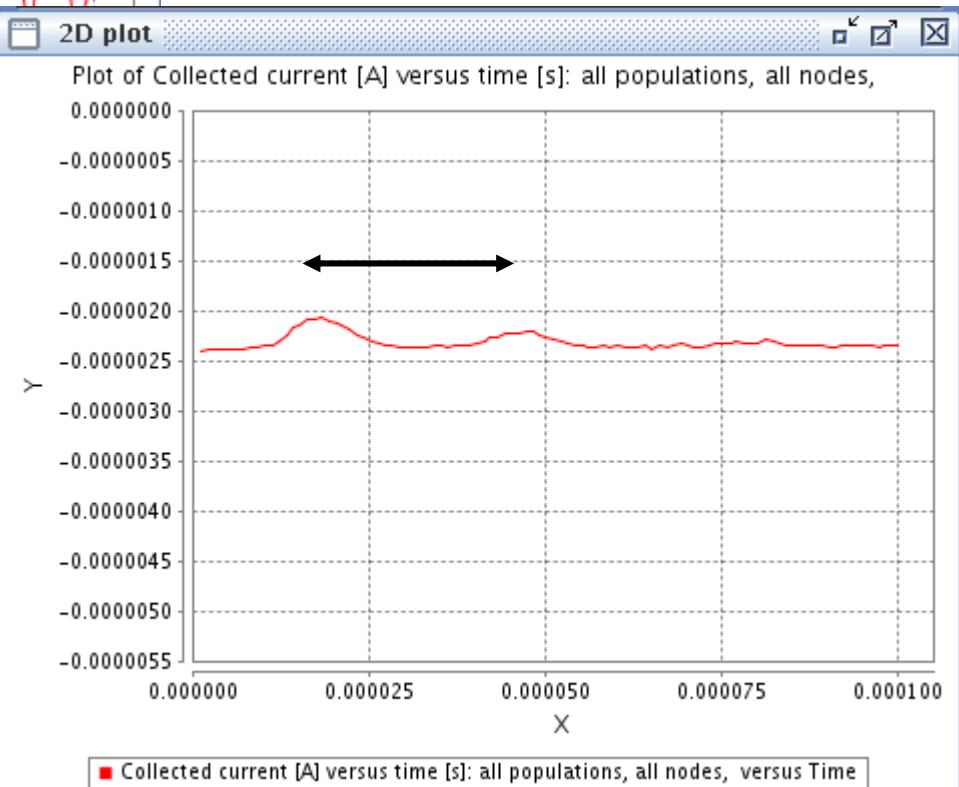
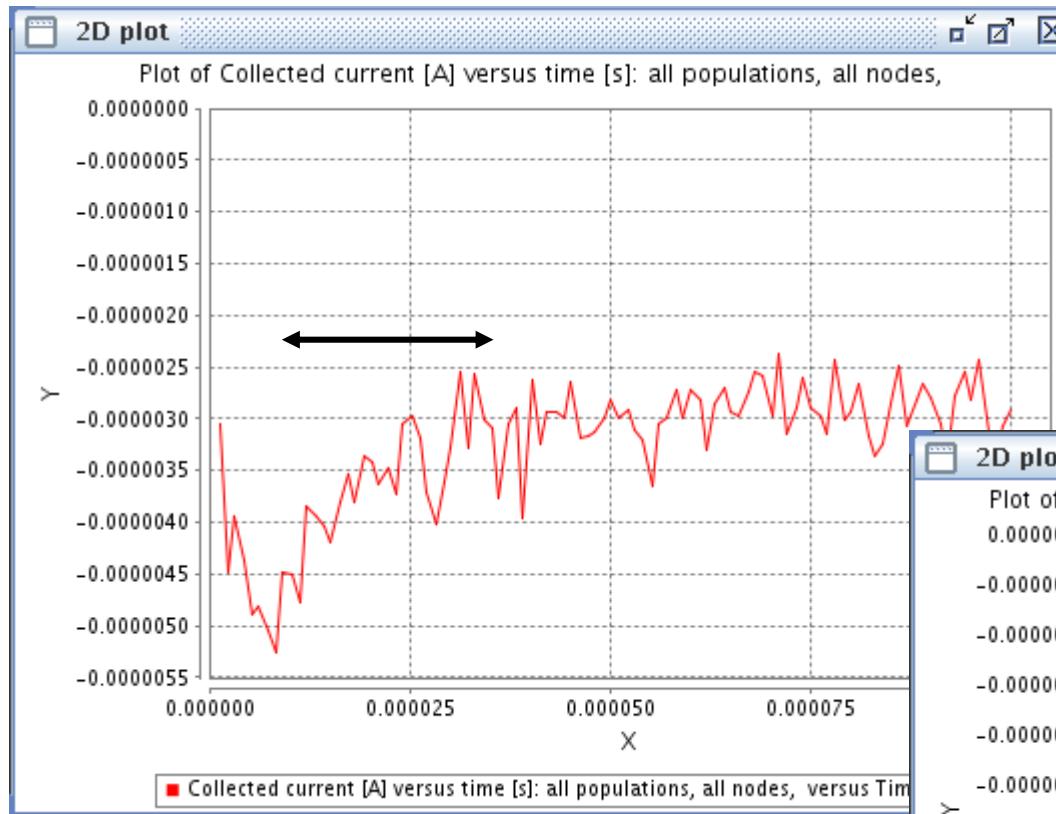
Errors

V	SPI3%	SPI4 Backtracking%
0	-3.49	-0.31
2	-3.33	-1.88
4	-5.38	-0.83
6	-4.03	-2.50
8	-4.33	-2.00
10	-4.52	-1.89
12	-4.65	-2.28



Errors

V	SPIS4 Backtracking%
0	0.31
-1	3.02
-2	13.7
-3	13.0
-4	7.49
-5	4.57
-6	2.43
-8	1.93
-10	3.60
-12	4.19



Electromagnetics & Space
Environment Division – TEC-EES

Conclusion

- Backtracking electron currents show good agreement with OML
- Results are improvement on PIC method
- Both electron and ions currents have been validated
- Results are quasi-steady state solutions, even when the simulation has not converged
 - Good if seeking steady state solution
 - Caution required if seeking dynamic behaviour

THE END



Electromagnetics & Space
Environment Division – TEC-EES